

U.S. Department of Commerce, Patent and Trademark Office	Atty Docket No.	Serial No.
	M-10700 US	09/741,663
INFORMATION DISCLOSURE STATEMENT BY APPLICANT		Applicant(s)
(Use several sheets if necessary)		Andrei V. Shchegrov et al.
Filing Date		Group
December 19, 2000		2877

U.S. Patent Documents

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>QW</i>	AA	5,751,427	5/12/98	de Groot			
<i>QW</i>	AB	6,268,916	7/31/01	Lee et al.			
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

Foreign Patent Documents

							Translation	
		Document	Date	Country	Class	Subclass	Yes	No
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)

<i>QW</i>	AQ	International Search Report for corresponding PCT application No. PCT/US01/49001 dated April 18, 2002.
	AR	
	AS	


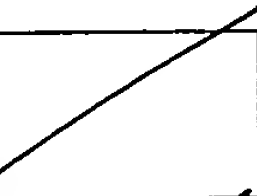
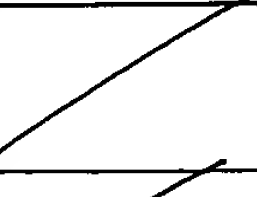
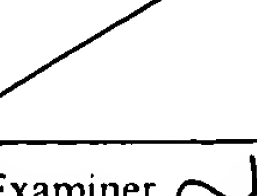

Examiner

QW

Date Considered

03/18/2004

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	5,963,329	10/5/99	Conrad et al.	356	372	10/31/97	
	AB							
	AC							
	AD							
	AE							
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	AG							
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	AM							
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	AP							
OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)								
	AQ	Patent Search conducted on August 1, 2000						
	AR	"Ultraviolet-visible ellipsometry for process control during the etching of submicrometer features," N. Blayo et al., <i>J. Opt. Soc. Am. A.</i> , Vol. 12, No. 3, March 1995, pp. 591-599						
	AS	"Algorithm Implementation and Techniques for Providing More Reliable Overlay Measurements and Better Tracking of the Shallow Trench Isolation (STI) Process," D. Schramm et al., <i>SPIE: Conference on Metrology, Inspection, and Process Control of Microlithography XIII</i> , March 1999, pp. 116-122						
Examiner 		Date Considered 03/18/2004						
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